ABSTRACT

Transfer Method for a Mask or Substrate, Storage Box, Device or Apparatus adapted for use in such Method, and Device Manufacturing Method comprising such a Method.

A method for transferring one or more substrates or masks in a storage box to a device or apparatus for handling, processing or using said substrates or masks or vice versa, said storage box comprising a cover having an openable cover part. The method comprises providing said storage box onto an openable wall part of a wall of an enclosed protective environment of said device or apparatus such that said openable cover part of said storage box overlaps said openable wall part of said protective environment, said protective environment being adapted to be filled with an inert gas or to be evacuated; opening said openable cover part of said storage box and said openable wall part of said protective environment, whereby said cover of said storage box forms part of said wall of said protective environment and an inside of said storage box becomes part of said protective environment; and transferring at least one of said substrates or masks from an inside space of said storage box to an inside space of said wall of said protective environment or vice versa.

Fig. 2

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